MYCRONIC

Built for world-class **photomasks**

The new FPS™ series





Laser path at optical rails

To ensure pattern quality on the photomask, a great treatment on laser beam is essential. Mycronic FPS series uses the same writing principle as other high-end mask writers from Mycronic and delivers superior image quality performance.

The FPS Evo series Full flexibility for multipurpose photomasks

The new generation FPS series is built on the Evo control platform. Updated with new, innovative software and hardware architecture, it's been designed for the future of production automation, advanced connectivity and big data applications.

IMPROVED STABILITY AND HIGHER UPTIME

New servo board with linear movement, simplified electronics with better performance and modern bus structure provide superior stability and better error handling to create higher system uptime.

SUPPORT FOR HIGHER LEVEL OF FACTORY AUTOMATION WITH VARIOUS LOADER SOLUTIONS

Newly developed PLS (Pre Loading System) and interface supporting communication from factory automation system minimize human interface, in order to reduce contamination and human error.

BETTER SUPPORT FOR LOGGING, CONNECTIVITY AND BIG DATA APPLICATIONS

New servo board logs all motions in system which can be analyzed and used for many different purposes. This enables stable system operation and extension to big data applications.

EXTENDABLE WITH NEW FUNCTIONALITY

Built on completely new modern hardware and software architecture, it enables development of new functions to meet customers' future demand.



FPS 6100 Evo & FPS 6100E Evo **Improved stability, higher** speed and lower costs for the advanced multi-purpose market

Advanced photomasks for the multi-purpose market have continuously adapted to the requirements driven by electronics component miniaturization, while at the same time operating in a cost sensitive market space. Reliable and well proven, the FPS 6100 Evo is used by some of the world's leading photomask manufacturers purpose market. to achieve superior image quality and productivity for advanced multi-purpose applications.

The FPS series has field-proven stability, high productivity and great writing guality, and is now re-launched with the FPS 6100 Evo and FPS 6100E Evo - designed to achieve superior image quality and productivity and, win the competition within multi-

FPS 6100 EVO FOR CHROME MASK

KEY SPECIFICATIONS	LEVEL 80	LEVEL 60	LEVEL 40	LEVEL 25	LEVEL 20	LEVEL 15
Writing speed (mm ² /min)	525	1250	2 600	6 000	8 000	12 000
XT mode (mm ² /min)	650	1500	4 500	8 500	12 000	20 000
Minimum lines and spaces (pitch/2)	0.75 µm	1.2 µm	2.0 µm	3.5 µm	5.0 µm	7.0 µm
CD Uniformity (3σ)	30 nm	40 nm	60 nm	80 nm	100 nm	200 nm
Pattern butting (3σ)	60 nm	60 nm	80 nm	100 nm	150 nm	170 nm
Overlay (3σ)	70 nm	85 nm	100 nm	120 nm	140 nm	160 nm
Max. mask size (mm)	813x813					

FPS 6100E EVO FOR EMULSION MASK

KEY SPECIFICATIONS	LEVEL 25	LEVEL 20	LEVEL 15	
Writing speed (mm ² /min)	5 000	10 000	12 000	
Minimum lines and spaces (pitch/2)	1.6 µm	2.1 µm	2.4 µm	
CD Unformity (3σ)	250 nm	350 nm	450 nm	
Pattern butting (3ơ)	200 nm	300 nm	400 nm	
Overlay (3σ)	120 nm	140 nm	160 nm	
Max. mask size (mm)	813x813			



KEY HIGHLIGHTS:

- 6 different optical levels for chrome mask writer
- 3 different optical levels for emulsion mask writer
- compared to standard mode
- Various loader solutions: MLU, HMU and fully automated PLS
- Various configurable options that customer can choose depending on users' business strategy



• XT mode for FPS 6100E to enhance writing speed up to 73%



FPS 8100 Evo Scale up your capability

The FPS 8100 Evo is our high-end solution for mask producers who want all the flexibility of the FPS concept but face new challenges relating to the microfabrication of LEDs, advanced electronic packages or fine metal mask applications. It is the best fit for users who want to have FPS 6100's flexibility and the perks of improved capability to take on new

FPS 8100 EVO FOR CHROME MASK

KEY SPECIFICATIONS	LEVEL 40	LEVEL 25	
Writing speed (mm ² /min)	4 500	6 500	
XT mode (mm ² /min)	6 000	10 000	
Minimum lines and spaces (pitch/2)	2 µm	3.5 µm	
CD Uniformity (30)	60 nm	80 nm	
Pattern butting (3ơ)	80 nm	100 nm	
Overlay (3σ)	100 nm	120 nm	
Max. mask size (mm)	1 100x1 660 and 1 400x1 620		



business opportunities that was previously limited because of stage size.

The FPS 8100 Evo has an 87% increase in writing area compared to the FPS 6100 Evo, which handles photomask to manufacture display generation 6 size of Fine Metal Mask.

Bringing tomorrow's electronics to life



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